PATENT



Applicant: Paul B. Mirkarimi et al.

Docket No.

: CIL-10972

Serial No. : 10/086,614

Art Unit

: 1762

Filed

: March 1, 2002

Examiner

: W. Markham

For

: Ion-Assisted Deposition Techniques For

The Planarization Of Topological Defects

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

CERTIFICATE OF MAILING UNDER 37 CFR 1.8(a)

I hereby certify that the attached correspondence comprising:

- Amendment (15 pages); 1.
- Petition for Extension (in duplicate);
- 3. Certificate of Mailing; and
- Return Postcard;

is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

> Mail Stop Amendment **Commissioner for Patents** P. O. Box 1450 Alexandria, VA 22313-1450

on August 16, 2005

John P. Wooldridge

(Type or print name of person mailing paper)

(Signature of person mailing paper)